

## ABSTRACT OF THE DISCLOSURE

An apparatus that inspects wire breaking of a semiconductor integrated circuit includes a voltage  
5 applying device (12), a light pulse source (14), a  
scanning device (16), an electromagnetic wave detection  
device (18), and a wire breaking detection device (20).  
The voltage applying device (12) maintains a semiconductor  
integrated circuit in a state where a predetermined  
10 voltage is being applied thereto. The light pulse source  
(14) generates an ultrashort light pulse (2). The  
scanning device (16) two-dimensionally scans and  
irradiates the two-dimensional circuit of the  
semiconductor integrated circuit by using the ultrashort  
15 light pulse (2). The electromagnetic wave detection  
device (18) detects an electromagnetic wave (3) radiated  
from a position irradiated with the ultrashort light pulse  
on the semiconductor integrated circuit. The wire  
breaking detection device (20) detects wire breaking of  
20 the irradiated position based on presence and absence or  
intensity of the electromagnetic wave.